

PTO/SB/21 (08-00)

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TRANSMITTAL		Application Number	10/618,024			
FORM		Filing Date	July 11, 2003			
(to be used for all correspondence after initial filing)		First Named Inventor	Robert P. Vaudo, et al.			
		Group Art Unit	ТВА			
		Examiner Name	ТВА			
Total Number of Pages in This Submission		Attorney Docket Number	ATMI-661			
	ENCLOSURES	(check all that apply)				
Fee Transmittal Form	Assigni	ment Papers	After Allowance Communication			
Fee Attached	Drawing	Application) L	to Group Appeal Communication to Board of			
Amendment / Reply			Appeals and Interferences Appeal Communication to Group			
After Final	Petition	ng-related Papers	(Appeal Notice, Brief, Reply Brief)			
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Response to Missing Parts/ Incomplete Application	Remarks					
Response to Missing Parts under 37 CFR 1.52 or 1.53						
SIG	NATURE OF APPLIC	ANT, ATTORNEY, OR AC	GENT			
Firm or William F. Ryan Individual name	nn, Reg. No. 44,313					
Signature		2				
Date 10/15/03						
CERTIFICATE OF MAILING						
I hereby certify that this correspondence is being deposited pursuant to 37 C.F.R. 1.8 in an envelope addressed to:						
Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on this date: Type or printed name Leg Ann DiLello						
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ATMI-661 CUSTOMER ID NO.: 25559

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Robert P. Vaudo, et al.

Group Art Unit: TBA

U.S. Application No.: 10/618,024

Examiner: TBA

Filed: July 11, 2003

Title: SEMI-INSULATING GAN AND METHOD OF MAKING THE SAME

CERTIFICATE OF MAILING

I hereby certify that this paper or fee is being deposited pursuant to 37 CFR 1.8

on the date indicated below and is addressed to the Commissioner of Patents, P.O. Box 1450, Alexandria, VA

22313-1450

10-16-2003

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

Pursuant to 37 C.F.R. §1.56, the attention of the Patent and Trademark Office is hereby directed to the reference(s) listed on the attached PTO-1449. It is respectfully requested that the information be expressly considered during the prosecution of this application, and that the reference(s) be made of record therein and appear among the "References Cited" on any patent to issue therefrom.

☑ 1. This Information Disclosure Statement is being filed within three months of the U.S. filing date OR before the mailing date of a first Office Action on the merits. No certification or fee is required in accordance with 37 CFR § 1.56 and § 1.97(b).

Applicant does not believe that any additional fee is due in connection with the foregoing. However, any deficiencies may be charged to the deposit account 50-0860.

Respectfully submitted,

William F. Ryann

Registration No. 44,313 Attorney for Applicant

Date: 10-15-2003
Advanced Technology Materials, Inc.
7 Commerce Drive
Danbury, CT 06810
Agent Ref: ATMI-661

FORM PTO-1449 US Dept. of Commerce Patent and Track Park (A) ATTORNEY DOCKET NO. SERIAL NO. ATMI-661 10/618,024 **APPLICANT** INFORMATION DISCLOSURE STATEMENT Robert P. Vaudo, et al. (use several sheets if necessary) FILING DATE GROUP July 11, 2003 **TBA** U.S. PATENT DOCUMENTS EXAMINER PATENT FILING/ INITIAL NUMBER ISSUE DATE NAME **CLASS SUBCLASS** PUBLICATION DATE IF APPROPRIATE BA 5,679,152 10/21/1997 Tischler, et al. BB 6,156,581 12/5/2000 Vaudo, et al. BC 6,440,823 8/27/2002 Robert P. Vaudo, et al. BD 6,447,604 9/10/2002 Flynn, et al. BE 6,488,767 12/3/2002 Xu, et al. BF 6,533,874 3/18/2003 Vaudo, et al. BG 20010008656 Tischler, et al. 7/19/2001 BH 20010055660 Tischler, et al. 12/27/2001 BI 20020028314 Tischler, et al. 3/7/2002 BJ 20020068201 Vaudo, et al. 6/6/2002 BK 6,596,079 7/22/2003 Vaudo, et al. FOREIGN PATENT DOCUMENTS DOCUMENT **PUBLICATION** TRANSLATION NUMBER DATE COUNTRY **CLASS SUBCLAS** YES S X (abstract only) OTHER DOCUMENTS (Including Author, Title, Journal-Date, Page Number, Etc.) Continue on Page **EXAMINER** DATE CONSIDERED EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.

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INITIAL		NUMBER	ISSUE DATE	NAME	CLASS	SUBCLASS	FILI /PUBLIC DA' IF APPRO	CATION TE	
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		APPLICANT	
		Robert P. Vaudo, et al.	
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